

Notice of References Cited	Application/Control No. 10/701,708	Applicant(s)/Patent Under Reexamination CHIANG ET AL.	
	Examiner Alexander Markoff	Art Unit 1746	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
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FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Handbook of Semiconductor wafer Cleaning Technology, Noyes Publications, 1993, pages 15-24, 44-56, 120-128, and 141-142.
	V	
	W	
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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